

Amendments to the Specification:

Please replace the paragraph beginning on page 4, line 24 of the Specification with the following replacement paragraph:

--In the micromechanical yaw rate sensor according to this specific embodiment, as in the known example according to Figure 2, annular flywheel 10 is connected with anchoring device ~~21, 21', 25~~ 22, 22', 25' via a flexural spring device made up of the two V-shaped flexural springs, in such a way that anchoring device 20 is located essentially in the center of the ring, so that annular flywheel 10 so that the annular flywheel is able to be displaced, elastically from its rest position, about the z axis, situated perpendicular to the surface of the substrate, and about the x and y axes, situated parallel to the surface of the substrate.--.

Please replace the paragraph beginning on page 4, line 32 of the Specification with the following replacement paragraph:

--However, anchoring device ~~21, 21', 25~~ 22, 22', 25' has two bases 21, 21' situated opposite one another and connected fixedly with substrate 100, and fashioned with a wedge shape at the opposed sides, bridge 25' connecting the two wedge tips with one another. Bridge 25' is suspended freely over substrate 100 from bases 21, 21'.--.